



PATENT  
ATTORNEY DOCKET NO. 07977/052001/US3053

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Hisashi Ohtani et al. Art Unit: 1765  
Serial No.: 08/690,747 Examiner: R. Kunemund  
Filed : August 1, 1996  
Title : METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

Box AF  
Assistant Commissioner for Patents  
Washington, DC 20231

AMENDMENT

Sir:

In response to the Official Action dated April 7, 1999,  
paper no. 9 in the above-referenced case, kindly amend the above-  
referenced application as follows:

In the Claims

Please amend the claims as follows.

1. (Amended) A method for manufacturing a  
semiconductor device comprising the steps of:

forming a non-single crystalline semiconductor film to  
become at least a channel forming region on an insulating  
surface;

patterning said semiconductor film into a patterned  
semiconductor film having peripheral portions;

Date of Deposit October 16, 1999

I hereby certify that this correspondence is being deposited with the  
United States Postal Service as **first class mail** with sufficient postage  
on the date indicated above and is addressed to the Assistant  
Commissioner for Patents, Washington, D C 20231.

Deborah Dean

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